

Form PTO-1449

Docket Number 356952000621

Application Number 10/024,957

INFORMATION DISCLOSURE CITATION  
IN AN APPLICATION

(Use several sheets if necessary)

Applicant

Nadim I. MALUF et al.

Filing Date December 18, 2001

Group Art Unit 3613

Mailing Date May 9, 2002

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## U.S. PATENT DOCUMENTS

**GROUP 3600**

Examiner Initials	Ref. No.	Date	Document No.	Name	Class	Subclass	Filing Date If Appropriate
W	1.	04/28/1908	886,045	Ehrlich et al.			
	2.	11/01/1932	1,886,205	Lyford			
	3.	09/12/1933	1,926,031	Boynton			
	4.	12/10/1946	2,412,205	Cook			
	5.	04/11/1950	2,504,055	Thomas			
	6.	06/24/1958	2,840,107	Campbell			
	7.	03/03/1959	2,875,779	Campbell			
	8.	05/01/1962	3,031,747	Green			
	9.	05/01/1973	3,729,807	Fujiwara			
	10.	07/24/1973	3,747,628	Holster et al.			
	11.	01/14/1975	3,860,949	Stoeckert et al.			
	12.	01/25/1977	4,005,454	Froloff et al.			
	13.	04/26/1977	4,019,388	Hall, II et al.			
	14.	05/17/1977	4,023,725	Ivett et al.			
	15.	05/01/1979	4,152,540	Duncan et al.			
	16.	01/01/1980	4,181,249	Peterson et al.			
	17.	11/03/1981	4,298,023	McGinnis			
	18.	07/27/1982	4,341,816	Lauterbach et al.			
	19.	03/06/1984	4,434,813	Mon			
	20.	04/08/1986	4,581,624	O'Connor			
	21.	12/16/1986	4,628,576	Giachino, et al.			
	22.	03/03/1987	4,647,013	Giachino, et al.			
	23.	04/28/1987	4,661,835	Gademann et al.			
	24.	09/20/1988	4,772,935	Lawler et al.			
	25.	04/18/1989	4,821,997	Zdeblick			
W	26.	04/25/1989	4,824,073	Zdeblick			

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27.	05/02/1989	4,826,131	Mikkor		
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29.	09/26/1989	4,869,282	Sittler, et al.		
30.	07/03/1990	4,938,742	Smits		
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32.	09/25/1990	4,959,581	Dantlgraber		
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34.	07/09/1991	5,029,805	Albarda et al.		
35.	08/06/1991	5,037,778	Stark et al.		
36.	09/24/1991	5,050,838	Beatty, et al.		
37.	10/08/1991	5,054,522	Kowanz, et al.		
38.	10/22/1991	5,058,856	Gordon, et al.		
39.	10/29/1991	5,061,914	Busch, et al.		
40.	11/12/1991	5,064,165	Jerman		
41.	11/19/1991	5,065,978	Albarda et al.		
42.	11/19/1991	5,066,533	America, et al.		
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49.	07/28/1992	5,133,379	Jacobsen et al.		
50.	09/01/1992	5,142,781	Mettner, et al.		
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57.	01/19/1993	5,180,623	Ohnstein		

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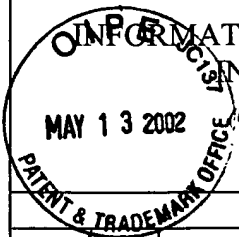
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58.	03/30/1993	5,197,517	Perera			
59.	05/11/1993	5,209,118	Jerman			
60.	06/01/1993	5,215,244	Buchholz et al.			
61.	06/01/1993	5,216,273	Doering et al.			
62.	06/08/1993	5,217,283	Watanabe			
63.	08/24/1993	5,238,223	Mettner et al.			
64.	09/14/1993	5,244,537	Ohnstein			
65.	12/07/1993	5,267,589	Watanabe			
66.	12/21/1993	5,271,431	Mettner, et al.			
67.	12/21/1993	5,271,597	Jerman			
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69.	05/10/1994	5,309,943	Stevenson et al.			
70.	07/05/1994	5,325,880	Johnson et al.			
71.	08/02/1994	5,333,831	Barth et al.			
72.	08/09/1994	5,336,062	Richter			
73.	10/18/1994	5,355,712	Petersen et al.			
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79.	10/17/1995	5,458,405	Watanabe			
80.	09/10/1996	5,553,790	Findler et al.			
81.	01/22/1996	5,556,703	Watanabe et al.			
82.	11/26/1996	5,577,533	Cook, Jr.			
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84.	09/22/1998	5,810,325	Carr			
85.	11/17/1998	5,838,351	Weber			
86.	12/15/1998	5,848,605	Bailey et al.			
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		Mailing Date May 9, 2002	

	07/27/1999	5,926,955	Kober		<b>RECEIVED</b> <b>MAY 16 2002</b> <b>GROUP 3600</b>
90.	08/24/1999	5,941,608	Campau et al.		
91.	02/01/2000	6,019,437	Barron et al.		
92.	08/22/2000	6,105,737	Weigert et al.		

## FOREIGN PATENT DOCUMENTS

Examiner Initials	Ref. No.	Date	Document No.	Country	Class	Subclass	Translation YES NO	
✓   								

## OTHER DOCUMENTS

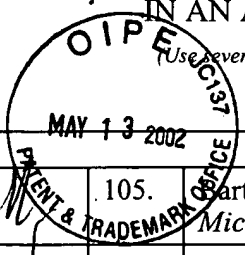
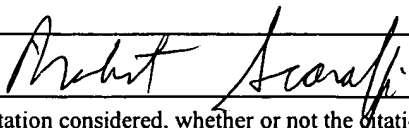
(including author, title, Date, Pertinent Pages, Etc.)

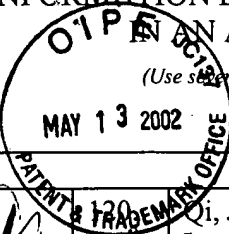
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	103.	Author Unknown. (Sept./Oct. 1999). "HiTecMetal Group Develops Niche Market for Brazed Laminated Assemblies," <i>Fluid Power Journal</i> 27.
	104.	Ayón, A.A. et al. (June 1998). "Etching Characteristics and Profile Control in a Time-Multiplexed ICP Etcher," <i>Proc. of Solid State Sensor and Actuator Workshop Hilton Head SC</i> pp. 41-44.

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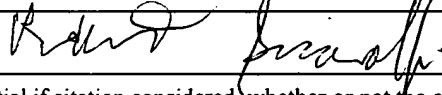
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105.	Bartha, J.W., et al., (1995). "Low Temperature Etching of Si in High Density Plasma Using SF <sub>6</sub> /O <sub>2</sub> ," <i>Microelectronic Engineering</i> , 27:453-456.		
106.	Carpenter Technology Corporation Tehcnical Data sheet for "Carpenter Low Expansion ;42", date November 1980 < <a href="http://www.carpenter.idesinc.com/datasheet.asp?e=181&amp;u=eVIEW=PRINTER">http://www.carpenter.idesinc.com/datasheet.asp?e=181&amp;u=eVIEW=PRINTER</a> > (visited on March 28, 2002).		
107.	Delphi Automotive Systems product brochure (1997). Variable Bleed Solenoid (VBS) for Transmission, copyright 1997.		
108.	Delphi Automotive Systems product brochure (1998). On/Off Transmission Solenoids, copyright 1998.		
109.	Duffy, James E. (1994). "Automatic Transmission Fundamentals," <i>Modern Automotive Technology</i> , copyright 1994, p. 707.		
110.	Fung, C.D., et al. (Nov. 7-8, 1984). "Deep Etching of Silicon Using Plasma," <i>Proceedings of the Workshop on Micromachining and Micropackaging of Transducers</i> , pp. 159-164.		
111.	Houston, P. N. et al. (June 1-4, 1999). "Low Cost Flip Chip Processing and Reliability of Fast-Flow, Snap-Cure Underfills," 1999 Electronic Components and Technology Conference. San Diego, CA, pp. 61-70.		
112.	Jonsmann, J. et al. (January 17-21, 1999). "Compliant Electro-thermal Microactuator" <u>Twelfth IEEE International Conference on Mico Electro Mechanical Systems</u> Orlando, Florida, IEEE Technical Digest entitled IEEE Catalog Number: 99CH36291C pp. 588-593.		
113.	Klaasen, E.H. et al.(1995). "Silicon Fusion Bonding and Deep Reactive Ion Etching; A New Technology for Microstructures," <i>Proc. Tranducers 95 Stockholm Sweden</i> pp. 556-559.		
114.	Konarski, Mark M. (May 31 to June 4, 1998). "Cure Parameter Effects on the Tg and CTE of Flip Encapsulants," 43rd International SAMPE Symposium and Exhibition. <i>Materials and Process Affordability. Keys to the Future.</i> Anaheim, CA, vol. 1 pp. 823-32.		
115.	Linder, C. et al. (June 1991). "Deep Dry Etching Techniques as a new IC Compatible Tool for Silicon Micromachining," <i>Proceedings, Transducers '91</i> pp. 524-527.		
116.	Madou, Marc (1997). "Scaling Laws, Actuators, and Power in Miniaturization," Chapter 9 <i>In Fundamentals of Microfabrication</i> CRC Press LLC: Boca Raton, FL., pp. 405-446.		
117.	Noworolski, J.M. et al., (1996) "Process for in plane-and out-of-plane single crystal-silicon thermal conductors" <i>Sensors and Actuators</i> 55(1):65-69.		
118.	Ohio State Univesity Chemistry Department brochure page on Marc J. Madou [online]. Ohio State University [retrieved on December 31, 2000]. Retrieved from the Internet: <URL: <a href="http://www.chemistry.ohio-state.edu/resource/pubs/brochure/madou.htm">http://www.chemistry.ohio-state.edu/resource/pubs/brochure/madou.htm</a> >.		
119.	Petersen, K.E. et al.(June 1991). "Surface Micromachined Structures Fabricated with Silicon Fusion Bonding," <i>Proceedings, Transducers '91</i> pp. 397-399.		
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<div style="display: flex;"> <div style="flex: 1;">  </div> <div style="flex: 2;"> <table border="1"> <tr> <td>120.</td> <td>Qi, J. and Johnson, W. et al. (April 6-9 1999) "Flip Chip on Laminate Manufacturability," 1999 International Conference on High Density Packaging and MCMs. Proc. SPEI - Int. Soc. Opt. Eng. (USA), Denver, CO., pp. 345-352.</td> </tr> <tr> <td>121.</td> <td>Search Report (March 15, 2000) PCT/US 99/19971.</td> </tr> <tr> <td>122.</td> <td>Williams, K. R. et al. (June 7-10, 1999). "A Silicon Microvalve for the Proportional Control of Fluids," <i>Transducers'99</i> Sendai, Japan., pp.1804-1807.</td> </tr> <tr> <td>123.</td> <td>Yunkin, V.A., et al. (1994). "Highly Anisotropic Selective Reactive Ion Etching of Deep Trenches in Silicon," <i>Microelectronic Engineering</i> 23:373-376.</td> </tr> </table> </div> </div>				120.	Qi, J. and Johnson, W. et al. (April 6-9 1999) "Flip Chip on Laminate Manufacturability," 1999 International Conference on High Density Packaging and MCMs. Proc. SPEI - Int. Soc. Opt. Eng. (USA), Denver, CO., pp. 345-352.	121.	Search Report (March 15, 2000) PCT/US 99/19971.	122.	Williams, K. R. et al. (June 7-10, 1999). "A Silicon Microvalve for the Proportional Control of Fluids," <i>Transducers'99</i> Sendai, Japan., pp.1804-1807.	123.	Yunkin, V.A., et al. (1994). "Highly Anisotropic Selective Reactive Ion Etching of Deep Trenches in Silicon," <i>Microelectronic Engineering</i> 23:373-376.
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